Field-E ect Transistors on Tetracene Single Crystals

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We report on the fabrication and electrical characterization of eld-e ect transistors at the surface of tetracene single crystals. We indicate the mobility of these transistors reaches the room - tem perature value of 0.4 cm² =V s. The non-m onotonous tem perature dependence of the mobility, its weak gate voltage dependence, as well as the sharpness of the subthreshold slope con in the high quality of single-crystal devices. This is due to the fabrication process that does not substantially a ect the crystal quality.

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C om m on strategies for the fabrication of organic elde ect transistors (FETs) are based on thin- lm technology [1, 2]. This choice is motivated by the existing deposition techniques for organic thin lm s that facilitate device fabrication. At the same time, thin lm susually contain a considerable amount of structural imperfections, which a ect negatively the transistor perform ance [3].

For small organic molecules, crystalline Im s can be used to reduce the amount of structural defects. It has been found, however, that also the perform ance of transistors based on these Im s are a ected by structural imperfections, even when only one crystalline grain is present between source and drain [4]. This is due to disorder present in the rst few molecular layers, in contact with the substrate, which constitute the device active region [5]. For this reason, im proving the quality of organic thin- Im transistors (TFT s) requires highly ordered molecular Im s, in which the order extend up to the interface with the substrate.

An alternative route to the production of high-quality organic FETs is to fabricate devices on the surface of a free-standing single crystal of organic molecules. If a fabrication process that preserves the quality of the crystals [6, 7] can be developed, the resulting single-crystal FETs should perform better than their TFT counterpart. W hereas considerable amount of work is currently aim ing at im proving the quality of organic TFTs [2, 4, 5, 8, 9], the investigation of single-crystal organic FETs has received only limited attention [10, 11, 12, 13, 14].

In this paper we discuss the fabrication and electrical characterization of eld-e ect transistors at the surface of tetracene single crystals. The fabrication process is based on adhesion of pre-grown, free-standing crystals to a therm ally oxidized Si wafer on which source and drain electrodes are deposited in advance. As we will show, this process preserves the quality of the starting crystals. From the electrical evaluation of a large num ber of devices we nd that the mobility of the charge carriers (holes) in our single-crystal FETs is reproducibly high, reaching 0:4 cm²=V s in the best device. In addition, the observed tem perature and gate voltage dependence of the mobility as well as the subthreshold slope indicate that the perform ance of single-crystal devices com pare well to

the best existing organic thin Im transistors [3].

The FET fabrication involves two main steps: the growth of single crystals and the preparation of a substrate on which the crystal is subsequently placed [25]. Tetracene single crystals are grown by means of physical vapor deposition in a temperature gradient in the presence of a stream of A rgon gas. The set-up used for the crystal growth is similar to that described in ref. [15]. The source material is 98% pure tetracene purchased from Sigma-Aldrich. Crystals grown from as-purchased tetracene are used as source material for a subsequent re-growth process, which results in crystals of increased

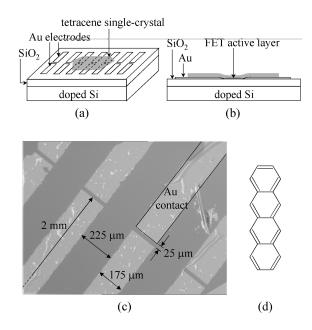


FIG.1: Schem atic representation (a) and side view (b) of a tetracene single-crystal FET. (c) Optical microscope im age of a tetracene single-crystal FET. In this device, the sem i-transparent tetracene single crystal extends over several pairs of electrodes, which are clearly visible under it. In most cases sm aller crystals have been used which extend over only one or two pair of contacts. These di erent con gurations allow us to study transistors with di erent W = L ratios on the sam e crystal. (d) M olecular structure of the tetracene molecule.

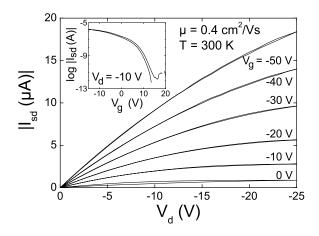


FIG.2: Source-drain current I_{sd} versus drain voltage V_d m easured at di erent values of V_g . The inset shows the dependence of log(I_{sd}) on V_g at xed V_d , for a di erent device, which has a mobility =0.05 cm $^2\text{=V}$ s and a threshold voltage V_t $^\prime$ 0.3 V . From this plot we calculate the subthreshold slope to be 1:6 V=decade.

chem ical purity. Tetracene crystals grown using physical vapor deposition are platelets. For the devices described in this paper we select thin (1 m thick) single crystals obtained by stopping the second re-growth process at an early stage.

The substrates used for the FET fabrication are highly doped (n-type orp-type) Siw afers, covered with a layer of 200 nm therm ally grown SiO₂. The conducting Siw afer serves as gate electrode, with the SiO₂ layer acting as gate insulator. Gold contacts are deposited on top of the SiO₂ by means of e-beam evaporation through a shadow mask (see g. 1 for the precise geometry and dimensions). The dimensions of the Au contacts as well as the tetracene crystal size determ ine the transistor channel length L and channel width W. This allows us to study transistors with di erent W =L ratios. Prior to placing the tetracene single crystals on top of the substrate, the SiO₂ surface is cleaned by R eactive Ion Etching (R IE) in an oxygen plasm a. W e found that this cleaning step is crucial for reproducible FET behavior [26].

Freshly grown tetracene crystals placed on RIEcleaned SiD₂ strongly adhere to the substrate. A dhesion only occurs for very thin crystals (1 m) that are su ciently exible and it is probably due to electrostatic forces. The crystals placed onto substrates are then inspected under an optical microscope using crosspolarizers. This allow sus to select single-crystalline sam – ples without visible defects for in depth electrical characterization [16]. The top view of a device fabricated following this procedure is shown in g. 1c.

W e have characterized more than ten single-crystal FETs exhibiting sim ilar overall behavior. E lectrical characterization is performed in the vacuum cham berofa ow cryostat at a pressure of 10 7 m bar, using a HP4156A Sem iconductor Param eter A nalyzer. The m easurem ents shown in this paper have been performed in a two-term inal con guration.

Fig. 2 shows the outcome of the measurements for one of the transistors with highest mobility. The current increases with increasing negative gate voltage. This indicates eld-e ect induced hole conduction, which is the expected behavior for tetracene. The eld-e ect mobility is evaluated in the linear regime of operation, where I_{sd} is proportional to V_d :

$$I_{sd} = \frac{W}{L} \qquad {}_{d}C \quad (V_{t} \quad V_{t}) \quad V_{t} \quad (1)$$

Here $C_{\rm d}$ is the capacitance per unit area of the SiD $_2$ layer and $V_{\rm t}$ is the threshold voltage. From equation 1 we obtain the mobility by calculating the derivative of $I_{\rm sd}$ with respect to both $V_{\rm d}$ and $V_{\rm g}$ and neglecting the dependence of on $V_{\rm d}$ and $V_{\rm g}$.

For all the FETs investigated we found room temperature values of the mobility larger than $0.01 \text{ cm}^2=V \text{ s.}$ In many cases > $0.1 \text{ cm}^2=V \text{ s}$ and the maximum mobility achieved so far is = $0.4 \text{ cm}^2=V \text{ s}$ (g. 2). This value is better than the highest mobility recently reported in tetracene TFTs and indicates the high quality of our single-crystalFETs [17].

The threshold voltage (de ned by equation 1) is positive in all our devices. It ranges from 0 V to 30 V and is typically V_t ' 10 V [27]. We do not norm ally observe a positive threshold voltage in FETs fabricated without the R IE cleaning, nor do we observe linear conduction through single crystals contacted with evaporated gold contacts. These observations suggest that the current

owing at zero gate voltage is not due to conduction through the crystal bulk (i.e. crystal doping) but rather to charge accumulated at the surface [18]. We believe that the charge accumulation is induced by the electrostatic adhesion of tetracene crystals to the R IE cleaned SiD₂ surface.

As an additional characterization of the single crystals FETs, the inset of g. 2 shows $\log(I_{sd})$ versus V_g at xed drain voltage ($V_d = 10 \text{ V}$). These data were measured on a FET with a relatively low mobility of $= 0.05 \text{ cm}^2$ =Vs, i.e. they can be considered as typical. From this measurement we nd the subthreshold slope to be 1:6 V=decade. Normalizing this value to the capacitance of the dielectric gives 28 V nF=decade dm These values are comparable to what is found for the best pentacene TFTs (15 80 V nF=decade dm [11, 17, 18]).

Further proof of the high quality of the tetracene single-crystal FET is provided by the temperature dependence of the mobility. Temperature dependent m easurem ents were performed in the range 220 330 K, since for T > 330 K tetracene crystals rapidly sublime at the pressure present in the measurement chamber, and for T < 200 K, a structural phase transition [19] offen results in a lowered mobility and in damage to the devices. Fig. 3 shows data from two di erent FETs. The mobility

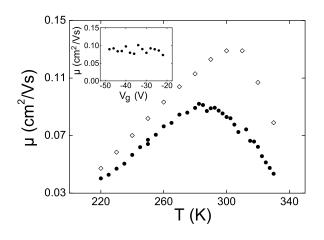


FIG. 3: Tem perature dependence of the eld-e ect m obility for two di erent devices, m easured at large negative gate voltage. The inset illustrates that at large negative gate voltage, 20 to 50 V, where the highest m obility is observed, is

essentially independent of V_g .

initially increases with lowering tem perature from 330 K to 280 300 K, and then decreases when the tem perature is low ered further. Such a non-m onotonous tem perature dependence is not usually observed in organic TFTs, which typically exhibit a therm ally activated decrease of

with decreasing T, over the entire tem perature range investigated [17, 20].

The observed tem perature dependence of the mobility is qualitatively sim ilar to the one expected for high-purity organic crystals in the presence of shallow traps, which is given by $/ T^{n} \exp(E_t=kT)$ [21, 22]. As long as E_t is not much larger than kT, this formula accounts

To obtain more information about the quality of the tetracene crystals and about the FET fabrication process, we have perform ed tim e-of-ight (TOF) measurements on several thick (100 200 m) tetracene crystals grown by the same technique [23]. For all crystals investigated, the room temperature mobility found in TOF experiments ranges from 0:5 to 0:8 cm 2 =V s, com parable or slightly higher than that obtained from our best FETs. A loo the tem perature dependence of the m obility is similar to that observed in FET measurements [24]. Finding comparable values for the bulk and the surface m obility [28] suggests that the FET fabrication process does not severely degrade the quality of the crystal surface. W e conclude that, presently, the lim iting factor for the mobility of the tetracene single-crystal FETs is the quality of the as grown crystals.

In conclusion, we have show n that high-quality organic single-crystal FETs can be realized, whose perform ance is comparable to the best existing organic thin Im transistors. As research on organic thin Im FETs has now been going on for many years whereas work on single crystals has just started, we consider this result to be particularly prom ising for future developm ents.

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- [26] W ithout R IE cleaning we observe a large spread in m obil-

ities, which are on average much lower than the mobility of FETs made on RIE cleaned substrates. Additionally, we nd much larger hysteresis in the electrical measurements and a large negative threshold voltage.

- [27] For holes, a positive threshold voltage implies conduction through the device in the absence of an applied gate voltage.
- [28] TOF experiments give a measure of the bulk mobility of charge carriers in the c-direction of the crystal, whereas FET experiments probe the mobility of charge carriers at the crystal surface.